

<b>Notice of References Cited</b>	Application/Control No. 10/539,250	Applicant(s)/Patent Under Reexamination VAN SCHAIJK ET AL.	
	Examiner David Goodwin	Art Unit 2818	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,130,453	10-2000	Mei et al.	257/315
*	B	US-6,093,606	07-2000	Lin et al.	438/259
*	C	US-5,386,132	01-1995	Wong, Chun C. D.	257/316
*	D	US-5,258,634	11-1993	Yang, Ming-Tzong	257/316
*	E	US-6,998,313	02-2006	Lin, Chi-Hui	438/270
*	F	US-6,465,836	10-2002	Lin et al.	257/315
*	G	US-5,739,567	04-1998	Wong, Chun Chiu D.	257/316
*	H	US-5,847,425	12-1998	Yuan et al.	257/315
*	I	US-7,056,792	06-2006	Lin, Chi-Hui	438/259
*	J	US-6,124,608	09-2000	Liu et al.	257/315
*	K	US-6,087,222	07-2000	Jung Lin et al.	438/259
*	L	US-5,751,038	05-1998	Mukherjee, Satyendranath	257/316
*	M	US-5,705,415	01-1998	Orlowski et al.	438/259

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.